

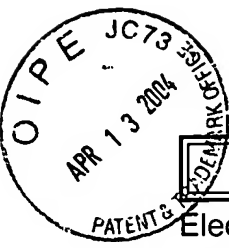
Electronic Filing System (EFS) Data
Electronic Patent Application Submission
USPTO Use Only

EFS ID: 58915
Application ID: 10725744
Title of Invention: SYSTEMS FOR INSPECTING
WAFERS AND RETICLES WITH
INCREASED RESOLUTION
First Named Inventor: Steven Lange
Domestic/Foreign Application: Domestic Application
Filing Date: 2003-12-02
Effective Receipt Date: 2004-04-13
Submission Type: Information Disclosure
Statement
Filing Type:
Confirmation number: 3066
Attorney Docket Number: 5589-05201




Total Fees Authorized:

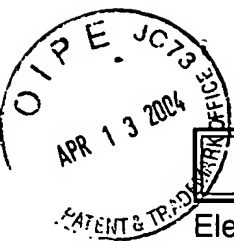
Digital Certificate Holder: cn=Kevin L. Daffer,ou=Registered Attorneys,ou=Patent and Trademark
Office,ou=Department of Commerce,o=U.S. Government,c=US
Certificate Message Digest: 38ef177129fedcb31655239ed03885bdac8e3fb3



TRANSMITTAL

Electronic Version v1.1
Stylesheet Version v1.1.0

Title of Invention	SYSTEMS FOR INSPECTING WAFERS AND RETICLES WITH INCREASED RESOLUTION									
<div>Application Number: 10/725744 </div> <div>Date: 2003-12-02</div> <div>First Named Applicant: Steven R. Lange</div> <div>Confirmation Number: 3066</div> <div>Attorney Docket Number: 5589-05201</div>										
<p>I hereby certify that the use of this system is for OFFICIAL correspondence between patent applicants or their representatives and the USPTO. Fraudulent or other use besides the filing of official correspondence by authorized parties is strictly prohibited, and subject to a fine and/or imprisonment under applicable law.</p> <p>I, the undersigned, certify that I have viewed a display of document(s) being electronically submitted to the United States Patent and Trademark Office, using either the USPTO provided style sheet or software, and that this is the document(s) I intend for initiation or further prosecution of a patent application noted in the submission. This document(s) will become part of the official electronic record at the USPTO.</p> <table border="1"><thead><tr><th>Submitted by:</th><th>Elec. Sign.</th><th>Sign. Capacity</th></tr></thead><tbody><tr><td>Kevin L. Daffer Registered Number: 34146</td><td>Kevin L. Daffer</td><td>Attorney</td></tr></tbody></table>			Submitted by:	Elec. Sign.	Sign. Capacity	Kevin L. Daffer Registered Number: 34146	Kevin L. Daffer	Attorney		
Submitted by:	Elec. Sign.	Sign. Capacity								
Kevin L. Daffer Registered Number: 34146	Kevin L. Daffer	Attorney								
<table><tr><td>Documents being submitted</td><td>Files</td></tr><tr><td>us-ids</td><td>5589-05201_IDS-usidst.xml</td></tr><tr><td></td><td>us-ids.dtd</td></tr><tr><td></td><td>us-ids.xsl</td></tr></table>			Documents being submitted	Files	us-ids	5589-05201_IDS-usidst.xml		us-ids.dtd		us-ids.xsl
Documents being submitted	Files									
us-ids	5589-05201_IDS-usidst.xml									
	us-ids.dtd									
	us-ids.xsl									
Comments										



ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of
Invention

SYSTEMS FOR INSPECTING WAFERS AND RETICLES
WITH INCREASED RESOLUTION

Application Number: 10/725744



Confirmation Number: 3066

First Named Applicant: Steven Lange

Attorney Docket Number: 5589-05201

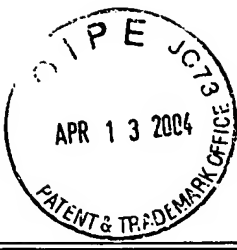
Search string: (5825043 or 6191429 or 5298939 or 4346164
or 6493156 or 5610683 or 5040020 or 4898804
or 4544626 or 4509852 or 5023424 or 5900354
or 5004307 or 5121256).pn.

US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	5825043	1998-10-20	Suwa			
	2	6191429	2001-02-20	Suwa			
	3	5298939	1994-03-29	Swanson et al.			
	4	4346164	1982-08-24	Tabarelli et al.			
	5	6493156	2002-12-10	Oh et al.			
	6	5610683	1997-03-11	Takahashi			
	7	5040020	1991-08-13	Rauschenbach et al.			
	8	4898804	1990-02-06	Rauschenbach et al.			
	9	4544626	1985-10-01	Sullivan			
	10	4509852	1985-04-09	Tabarelli et al.			
	11	5023424	1991-06-11	Vaught			
	12	5900354	1999-05-04	Batchelder			
	13	5004307	1991-04-02	Kino et al.			
	14	5121256	1992-06-09	Corle et al.			

Signature



Examiner Name	Date